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DISCLOSURE STATEMENT

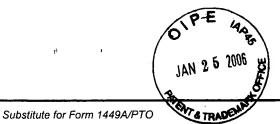
Application #	09/856,358
Confirmation #	6873
Filing Date	May 22, 2001
First Inventor	KEZUKA
Art Unit	1765
Examiner	Umez Eronini, Lynette T.
Docket #	P07223US00/BAS

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

SIR:

This following:	DS is submitted herewith pursuant to 37 CFR. §1.97-1.98 and includes the
A listing	of the references on PTO-1449.
	all non-US references which are listed on the PTO-1449 (US refs not required).
	a corresponding foreign Search Report which explains the relevance of the se noted therein.
A separa	te explanation of relevance.
Pleas	e note the following particulars concerning the filing of this IDS:
 within within §1.49 before 	OS is filed at whichever is the latest of: three months of the filing date of a NATIONAL APPLICATION other than a CPA, or three months of the date of entry into the NATIONAL STAGE as set forth in 37 CFR. 1 in an international application, or the mailing date of a first Office Action on the merits, or the mailing of a first Office Action after the filing of an RCE.
other acti	os is filed after a first Office Action , but <u>before</u> a Final Action, Allowance, or any on which closes prosecution, and : accompanied by a payment in the amount of \$180.00 required by 37 CFR. 17(p).
or_	w <i>'</i>
any mor C. I com my des	hereby state that each item of information contained in this IDS was first cited in communication from a foreign patent office in a counterpart foreign application not the than three months prior to the filing of this IDS. Thereby state that no item of information in this IDS herewith was cited in a munication from a foreign patent office in a counterpart foreign application, and, to knowledge after making reasonable inquiry, was known to any individual ignated in 37 CFR. §1.56(c) more than 3 months prior to the filing of this IDS.
∐ D. A	An appropriate Statement is attached.

3. T	his IDS is filed after a final action or all	owance, but on/before payment of the issue fee,
and		ne amount of \$180.00 required by 37 CFR.
and	any communication from a foreign pa more than three months prior to the f C. I hereby state that no item of infor communication from a foreign patent my knowledge after making reasonal	mation in this IDS herewith was cited in a office in a counterpart foreign application, and, to ble inquiry, was known to any individual than 3 months prior to the filing of this IDS.
	his IDS does not comply with 37 CFR operation of the pursuant to 37 CFR. §1.97(i)	1.97-1.98, and is being filed for placement in the
a. 	609; but if for some reason it does not requested to telephone the undersigne Some of the documents may have mar attached to those markings. These documents are not necessarily a	of an abstract is provided from a public source,
payı		ue in connection with this communication or if the nissioner is authorized to charge any fee or to Deposit Account No. 12-0555.
Date:	25 January 2006	Respectfully submitted, By: B. Aaron Schulman Registration No.: 31,877
STIT		Fairfax St. + Suite 900 + Alexandria, VA 22314



Customized PTO/SB/08a+b (07-05)

INFORMATION DISCLOSURE
STATEMENT BY APPLICANT

Sheet 1 of 1

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	U.S. PATENT DOCUMENTS				
Exam. Initial*	Document No. Number - Kind	Publ. Date MM-DD-YYYY	Name Patentee or Applicant	Relevance	
miliai	US-3,518,135	06-30-1970	CERNIGLIA ET AL	Passages/Figs.	
	US-4,395,304	07-26-1983	KERN ET AL		
	US-5,824,601	10-20-1998	DAO ET AL		
	US-5,571,375	11-05-1996	IZUMI ET AL		
	US-				
	US-				
	US-				

	FOREIGN PATENT DOCUMENTS					
Exam. Initial*	Country-Number-Kind	Publ. Date MM-DD-YYYY	Name Patentee or Applicant	Relevance Passages/Figs.	Trans- lation	
	WO 94/27314	11-24-1994	INTERUNIVERSITAIR ICROELEKTRONICA CENTRUM			
						

Exam. Initial*	Include NAME of the author (in CAPS), Title of Article/Item, Date, Page(s), Volume-Issue No., Publisher, City and/or Country where published	Trans-
	TAMIS et al; 'Characterisation of oxidation-induced stacking faults in soi structures by a new chemical etching process" January 1992; pgs. A193-A195; vol. 7; Semiconductor science and technology; United Kingdom	

Examiner Signature	Date Considered	

^{*} Examiner: Initial if considered, whether or not citation is in conformance with MPEP §609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.